

TESCAN VEGA

Analytical SEM for routine materials characterization, quality control and research applications at the micron scale.



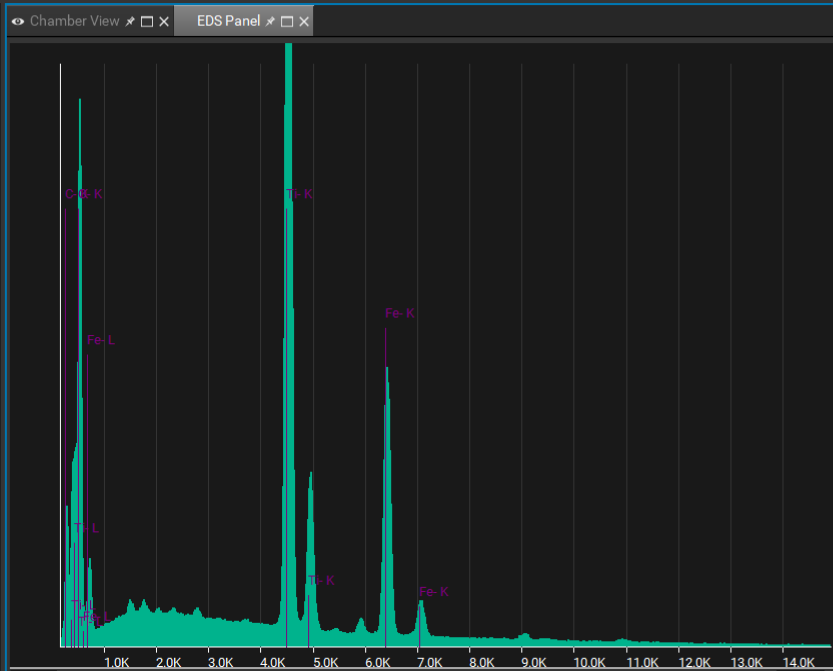
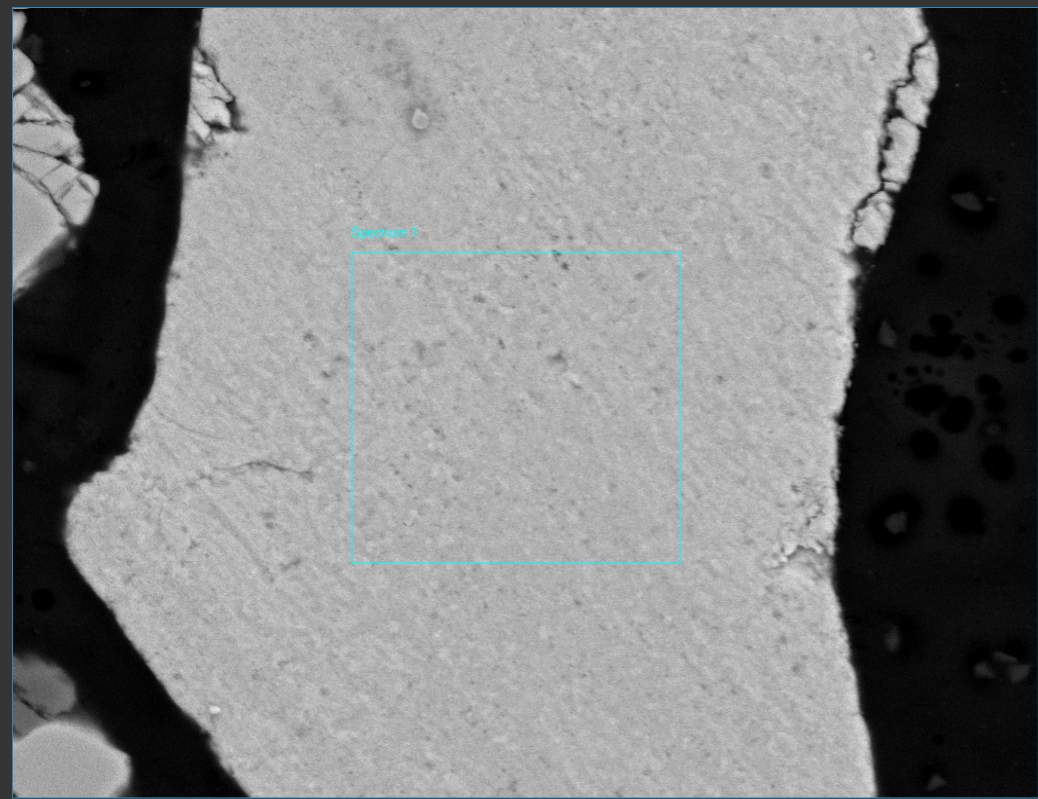
TESCAN VEGA

Analytical SEM for routine materials characterization, quality control and research applications at the micron scale.

- ✓ Analytical platform which efficiently combines SEM imaging with elemental composition analysis in single GUI using Fully integrated **Essence™ EDS**
- ✓ Optimum **imaging and analytical conditions immediately available** thanks to In-flight Beam Tracing™.
- ✓ Effortless and precise SEM navigation on the sample at very low magnifications thanks to the unique **Wide Field Optics™ design**
- ✓ Intuitive and modular **Essence™ software**
- ✓ Ultimate safety of the chamber mounted detectors when moving with the detectors - **Essence™ 3D Collision model**.
- ✓ **SingleVac™** as a standard feature for observation of charging and beam-sensitive samples.
- ✓ **Ecological and economic in use** thanks to vacuum buffer which significantly reduce of vacuum rotary pump run-time



Essence™ EDS Spectrum from region and point



H																	He	
Li	Be											B	C	N	O	F	Ne	
Na	Mg											Al	Si	P	S	Cl	Ar	
K	Ca	Sc	Ti	V	Cr	Mn	Fe	Co	Ni	Cu	Zn	Ga	Ge	As	Se	Br	Kr	
Rb	Sr	Y	Zr	Nb	Mo	Tc	Ru	Rh	Pd	Ag	Cd	In	Sn	Sb	Te	I	Xe	
Cs	Ba			Hf	Ta	W	Re	Os	Ir	Pt	Au	Hg	Tl	Pb	Bi	Po	At	Rn
Fr	Ra			Rf	Db	Sg	Bh	Hs	Mt	Ds	Rg	Cn						
			La	Ce	Pr	Nd	Pm	Sm	Eu	Gd	Tb	Dy	Ho	Er	Tm	Yb	Lu	
			Ac	Th	Pa	U	Np	Pu	Am	Cm	Bk	Cf	Es	Fm	Md	No	Lr	

Element	Atomic %	Weight %
Carbon	36.1%	19.84%
Iron	5.22%	13.33%
Oxygen	42.31%	30.97%
Titanium	16.38%	35.86%

58% DT 109k CPS
C: 1.5E+06

- Sample 1
 - Map 2
 - Line 1
 - Point 1
 - Spectrum 1

Pad

Working Distance: 14.66 mm

SEM Scan

SEM

Eng 20 keV MODE DEPTH
FoV 104.9 μm WD 14.66 mm
Spd 3 (1 μs) BC 10 nA

Low Vacuum
7 Pa 6.2E-04 Pa
27 Pa

Stage Control

Tilt: 0° 35° 55°
Rotation: +90° +180° -90°

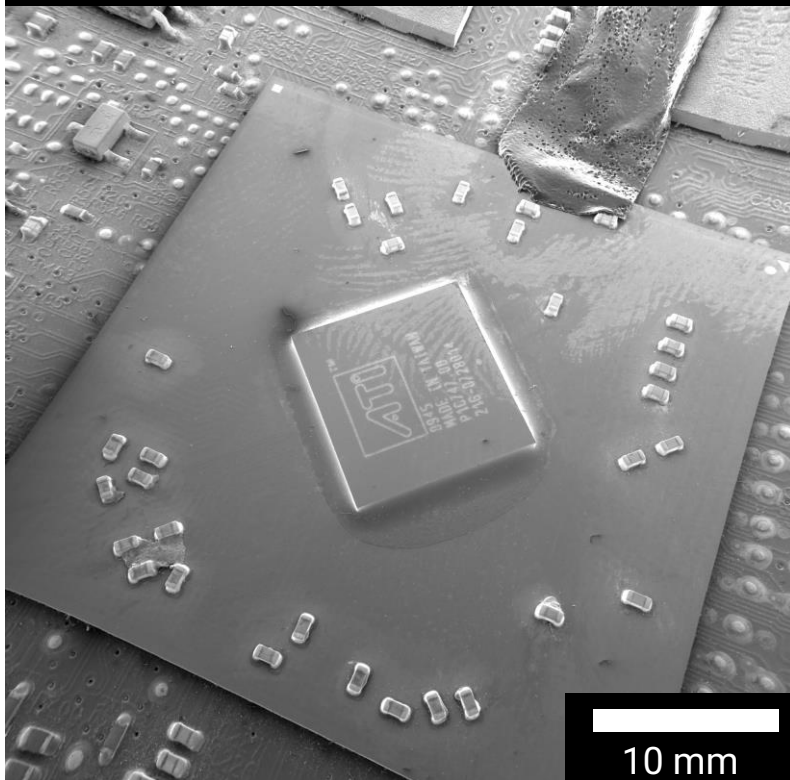
WD&Z
14.663 mm Move
Analytical 10 mm

A B C D E F G

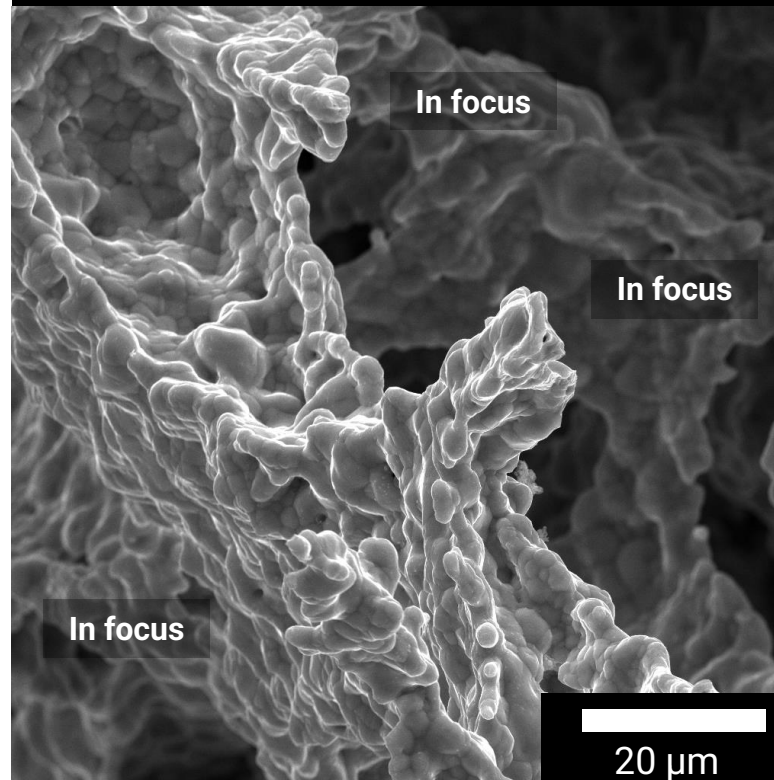
5 4 F2
6 7 F1
1 2

Unique Optics Design – Intermediate Lens™

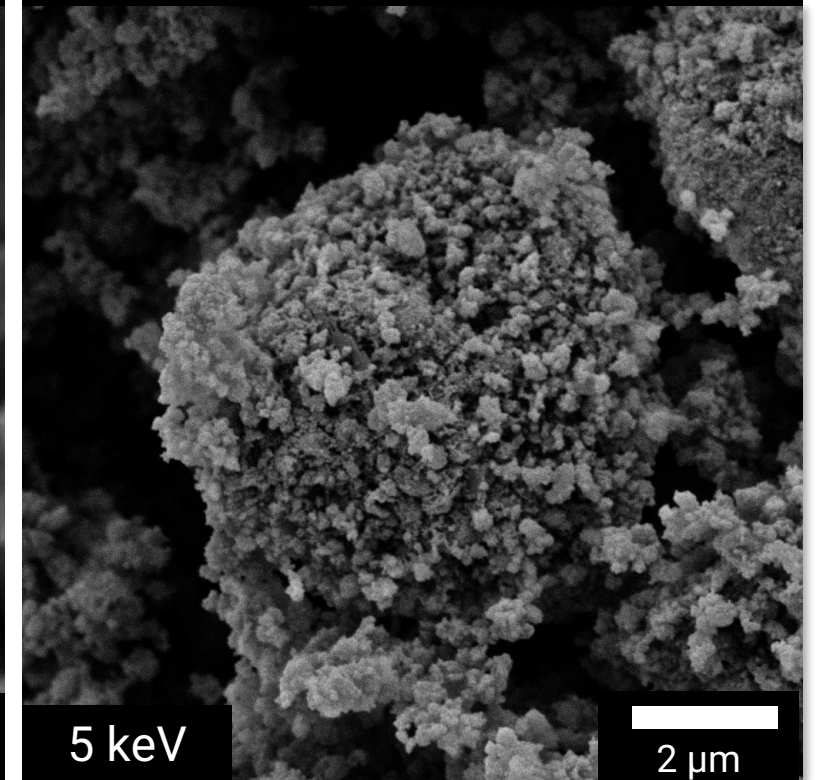
Wide Field Mode™

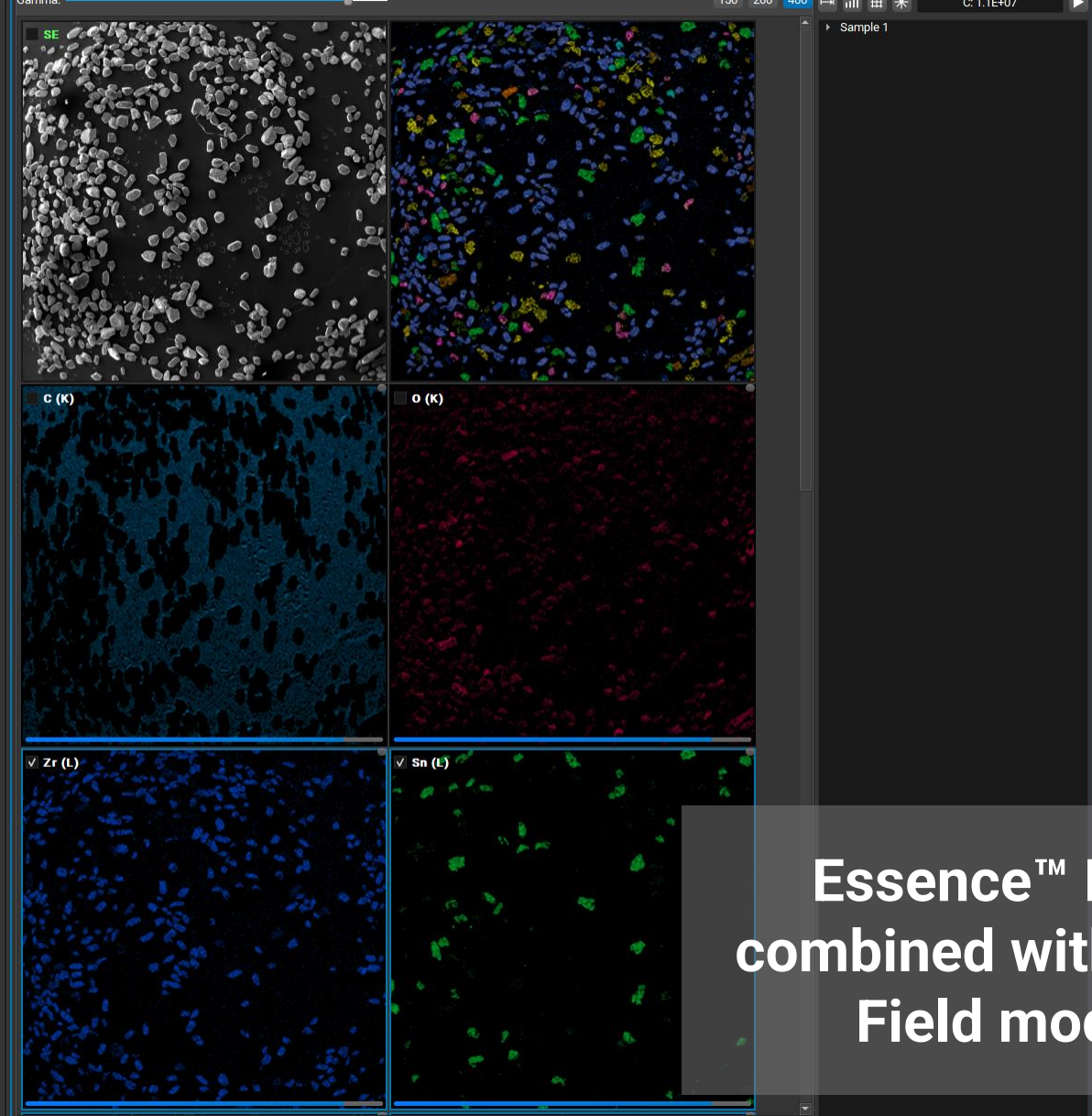
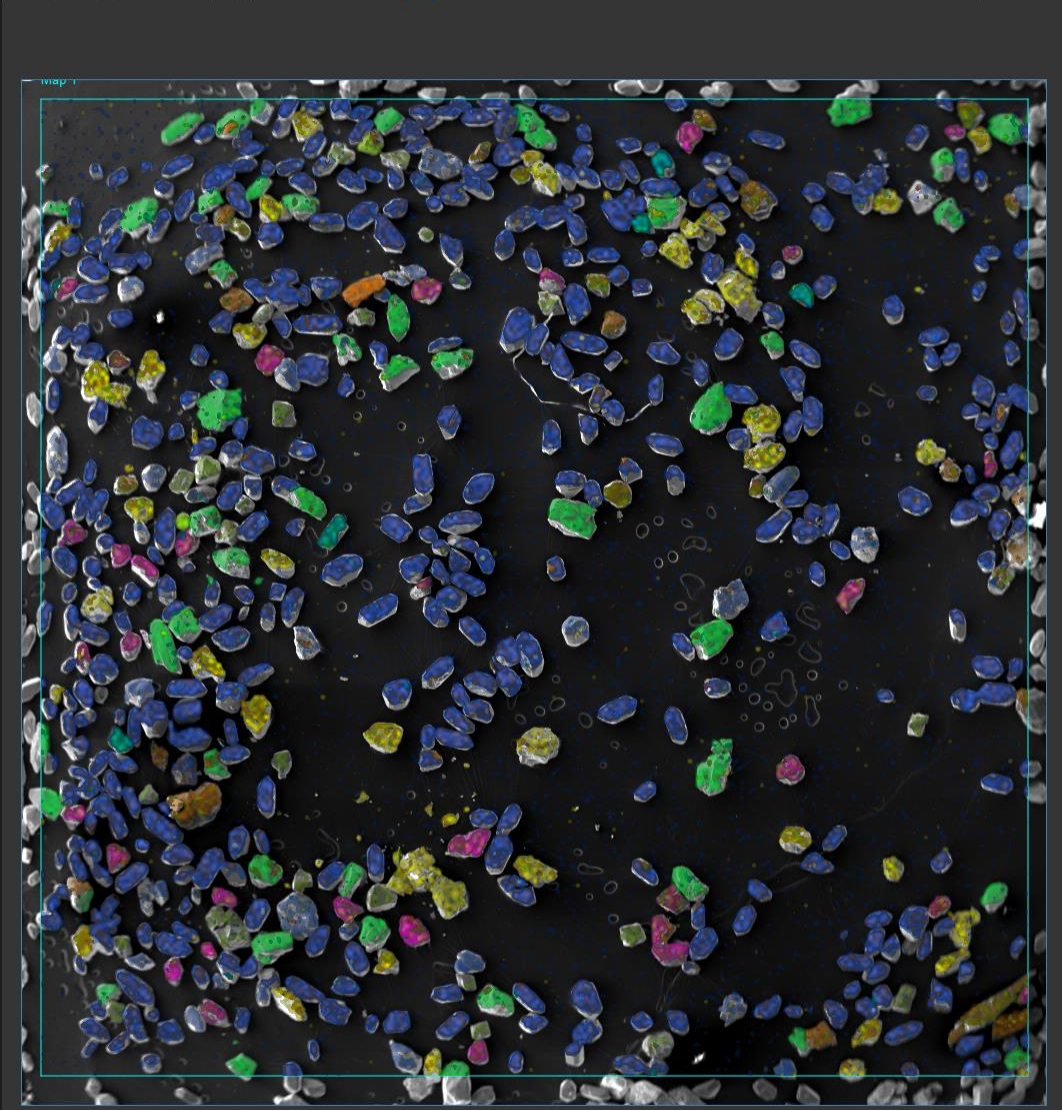


RESOLUTION and DEPTH Mode



Fast setup of imaging conditions





Working Distance 4

15 mm

SEM Scan

SEM

Preset: -----

Eng 20 keV WIDE FIELD

FoV 7793.6 μm WD 15 mm

Spd 4 (3.2 μs) BC 10 nA

Low Vacuum

7 Pa 3.6E-04 Pa

27 Pa

Stage Control

Stop

Tilt 0° 45°

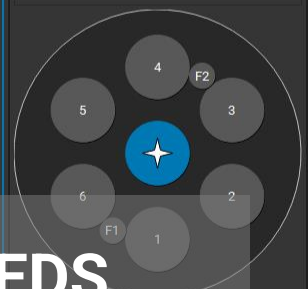
Rotation +90° +180° -90°

WD&Z

15 mm Move

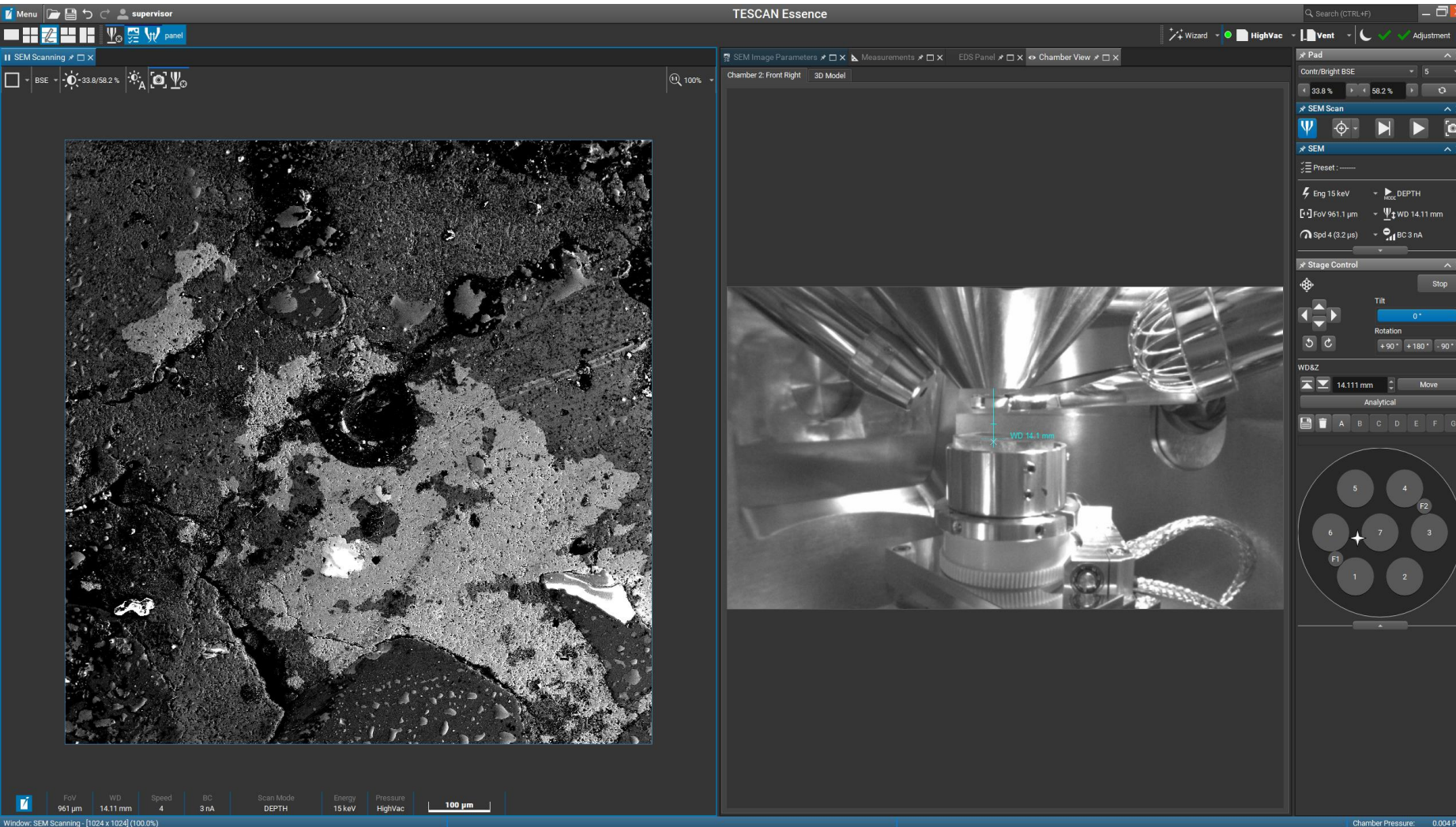
Analytical 10 mm 3.5 mm

A B C D E F G



Essence™ EDS
combined with Wide
Field mode

TESCAN Essence™ Software



Multiuser modular GUI

Application specific layout

Layout manager for image windows

Workflow-oriented wizards

3D collision model

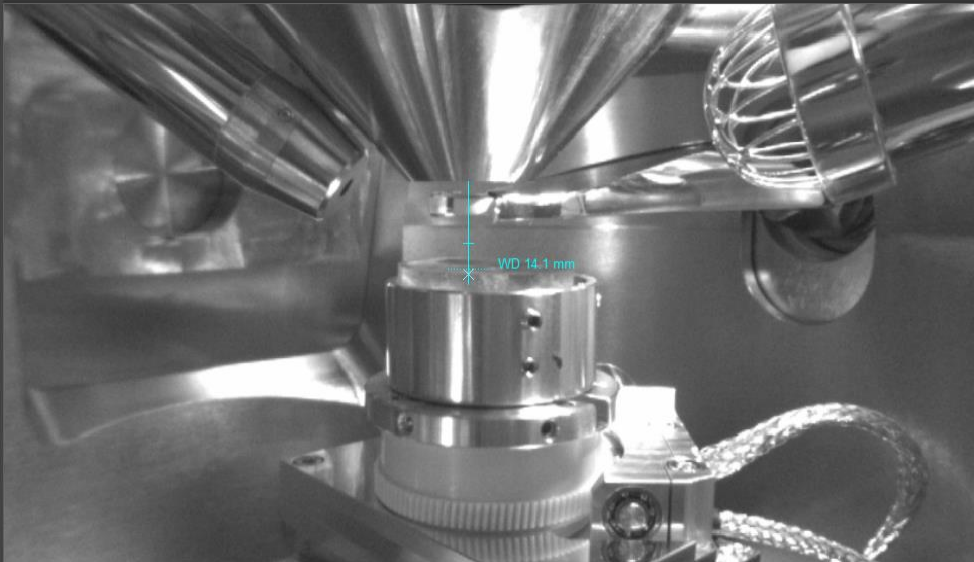
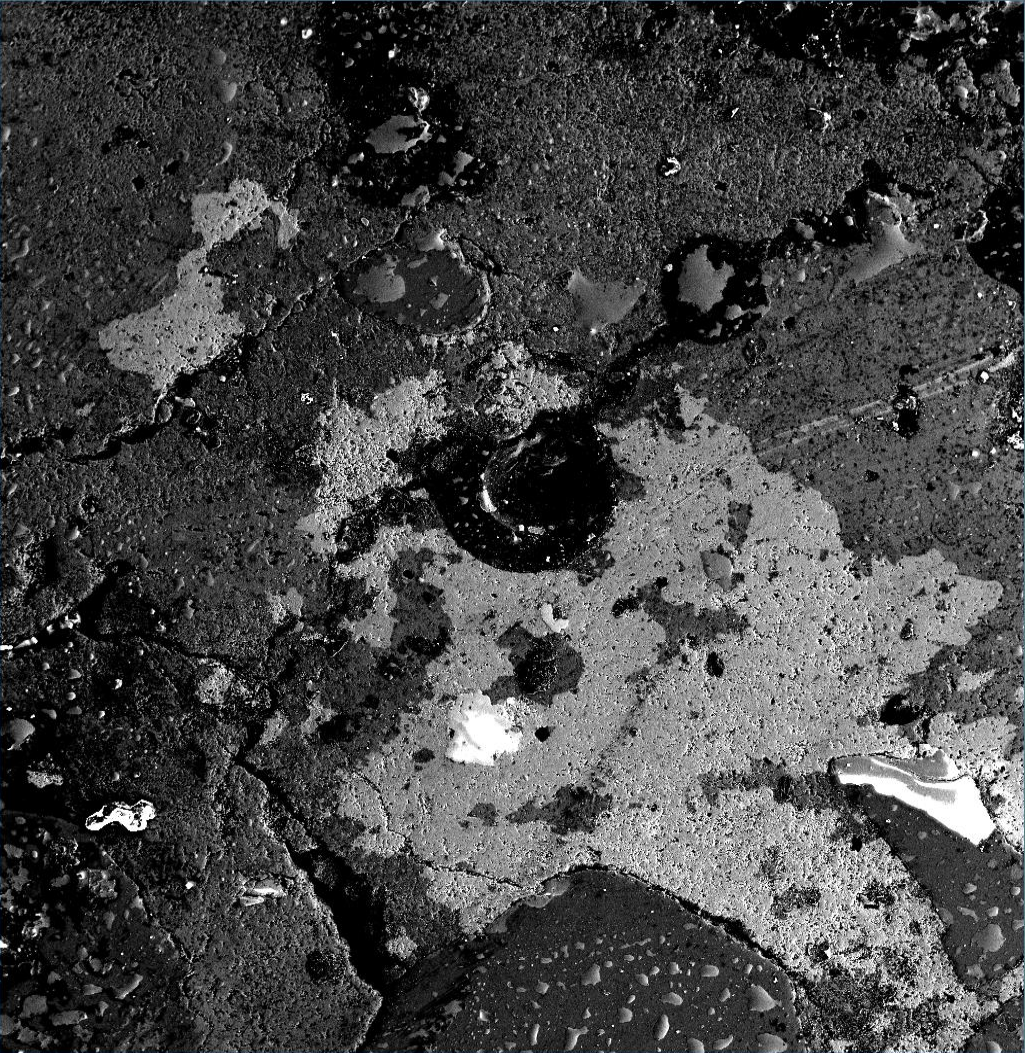
Quick search box

SEM undo commands

SEM Scanning 100%

SEM Image Parameters Measurements EDS Panel Chamber View

Pad Contr/Bright BSE 5 33.8% 58.2%

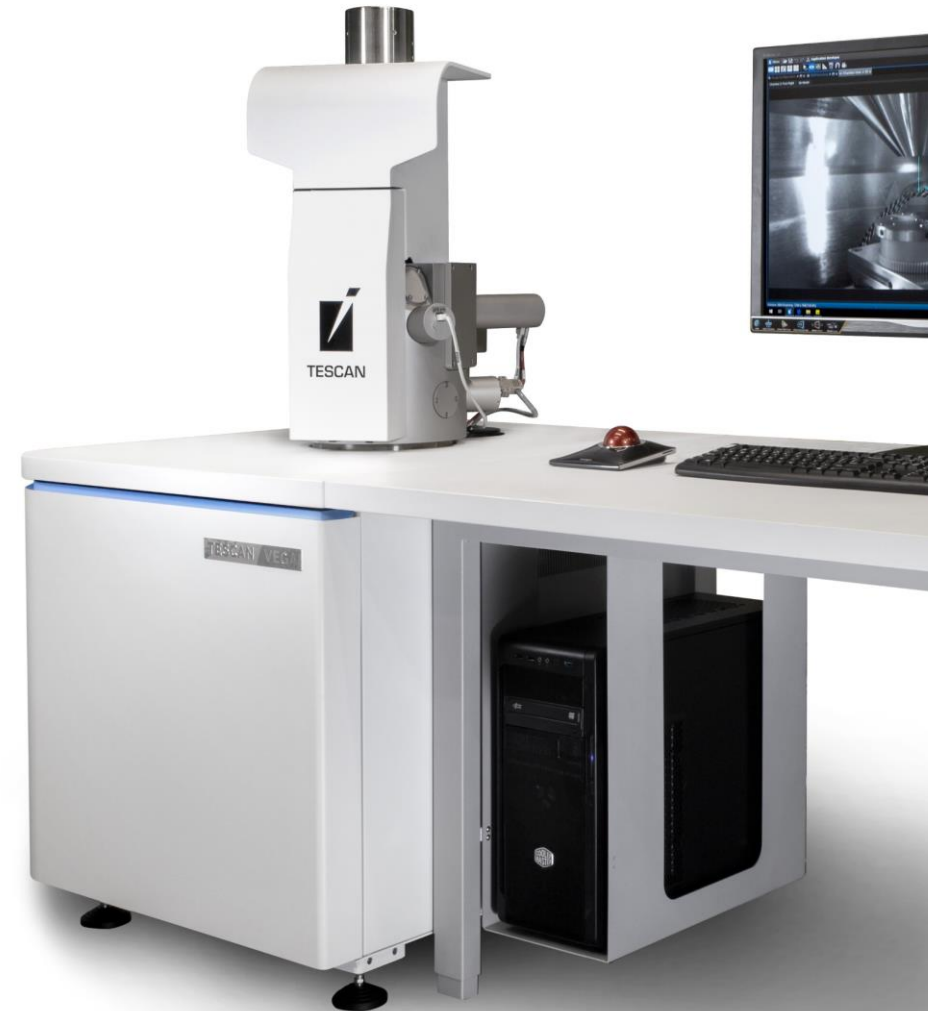


SEM Scan SEM SEM Preset: Eng 15 keV DEPTH FoV 961.1 µm WD 14.11 mm Spd 4 (3.2 µs) BC 3 nA Stage Control Tilt 0° Rotation +90° +180° -90° WD&Z 14.111 mm Analytical

TESCAN VEGA

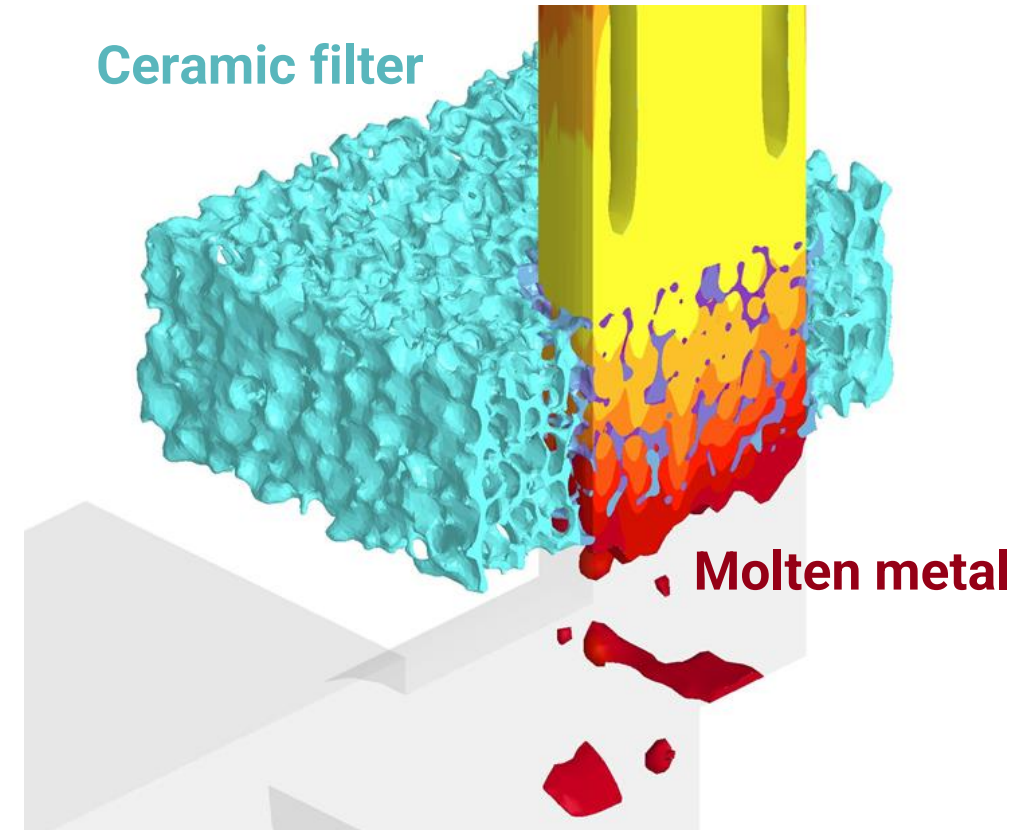
All these features makes your SEM imaging routine

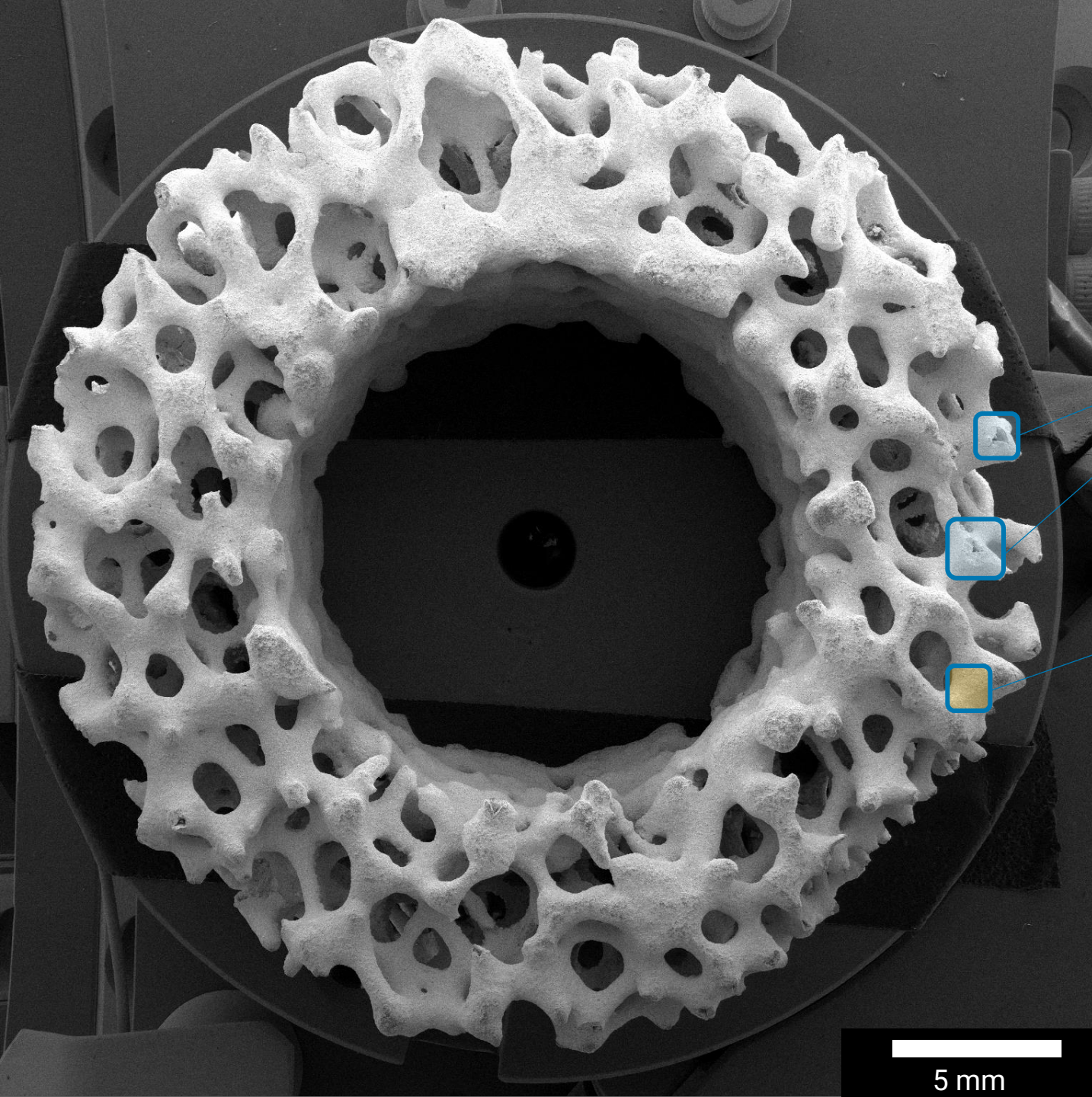
- ✓ **Faster** using Wide Field Mode™ and In-Flight Beam Tracing™
- ✓ **More Efficient** using integrated Essence™ EDS in live scanning window
- ✓ **More Intuitive** using Essence™ modular software



Evaluation of the Ceramic foam

- Ceramic foams have two principal applications
 - **As a ceramic filter** remove impurities from molten metal in the casting process at foundries.
 - **As a ceramic core** for castings from steel alloys and super alloys
- While produced mainly these factors are evaluated
 - Porosity
 - Cracks and adhesion of coatings
 - Overall morphology



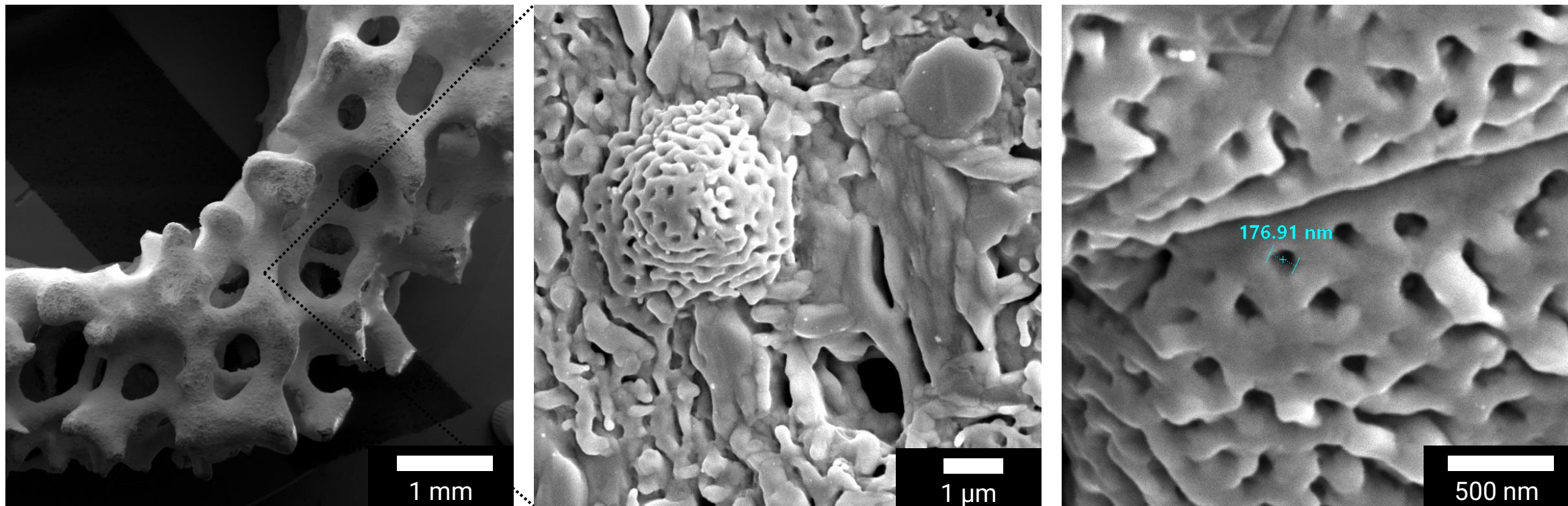


Locations where porosity may be evaluated
Locations where coating thickness and adherence can be analyzed

Locations where cracks in coating and coating adherence can be analyzed (all the surface)

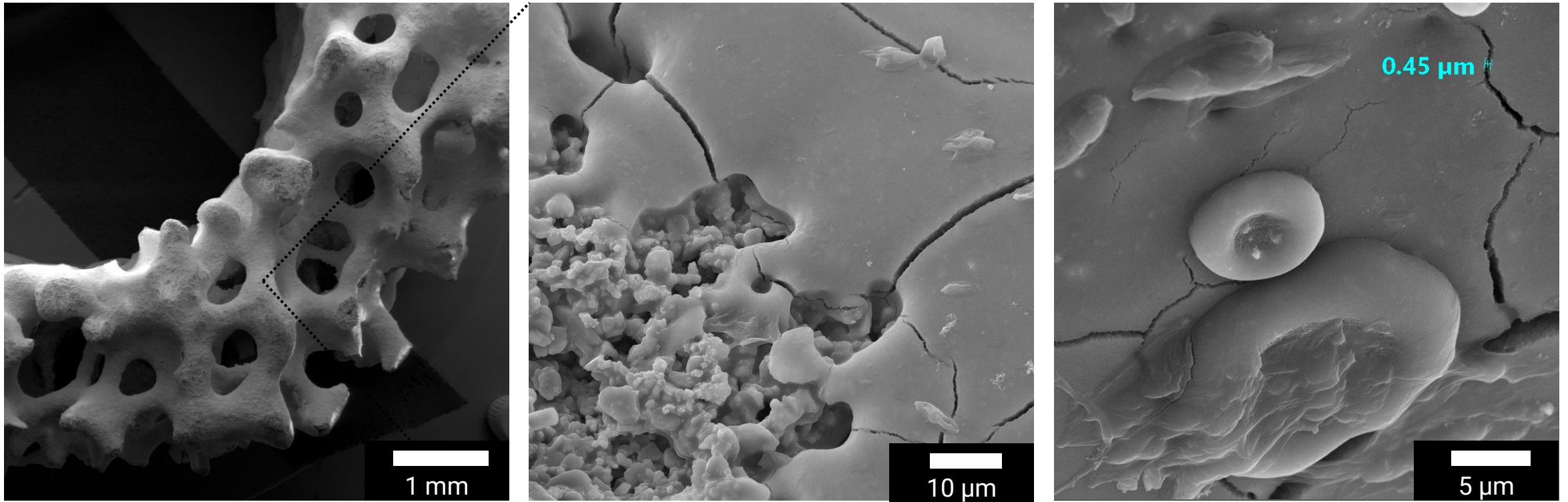
5 mm

Ceramic foam was sputter coated



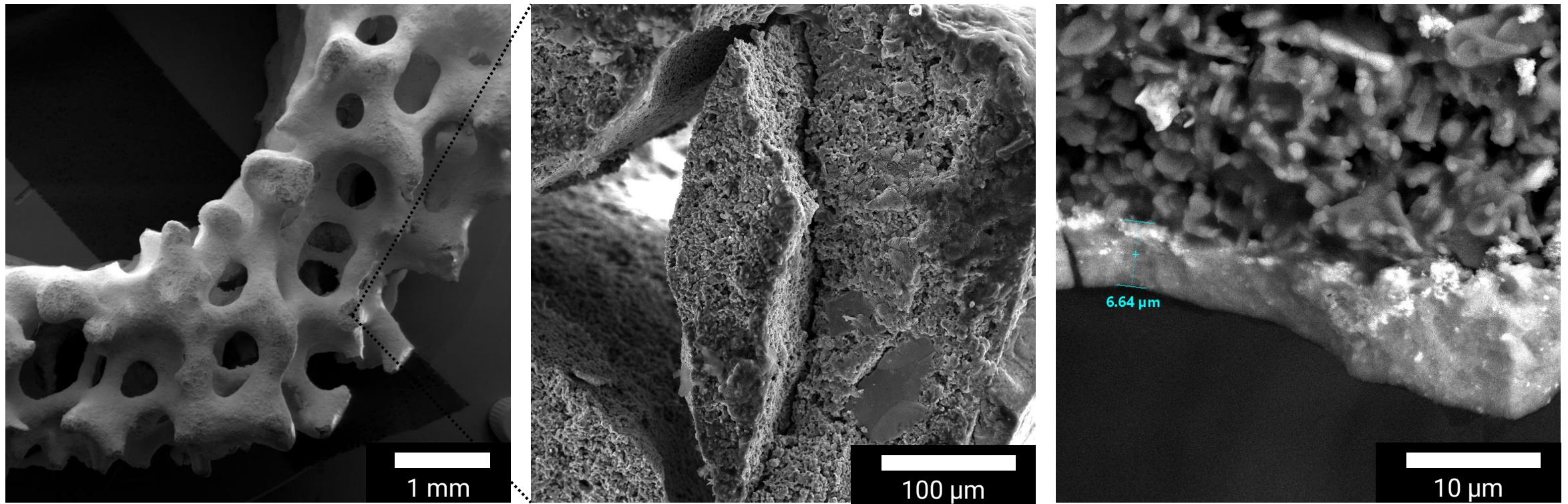
Analysis of pore size

Imaged at 15 keV with SE (left, middle) and BSE (right) detector



Analysis of Ti layer adherence and cracks

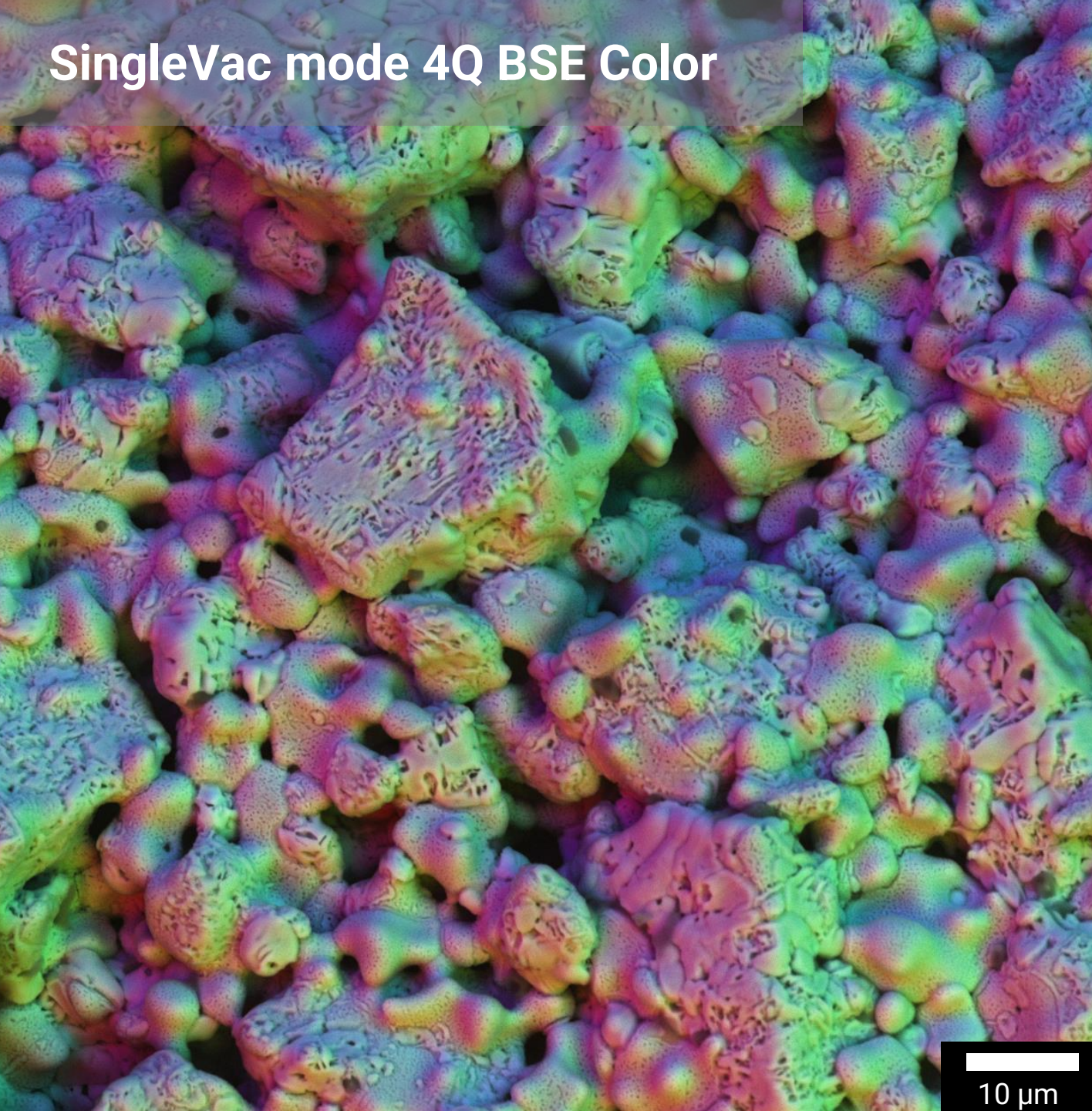
Imaged at 10 keV with SE detector



Ti Layer adherence and its thickness

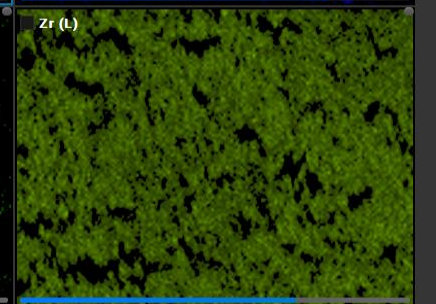
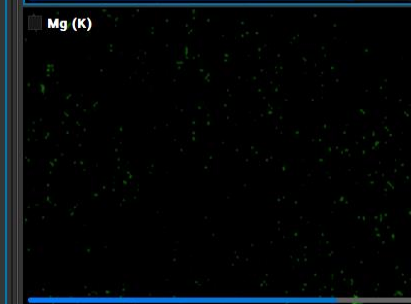
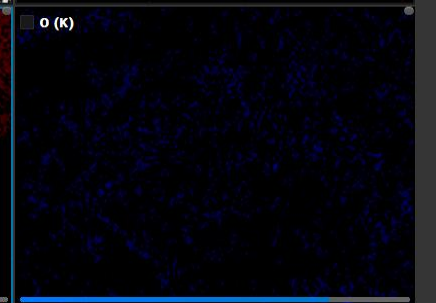
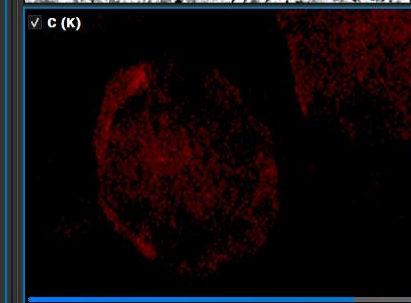
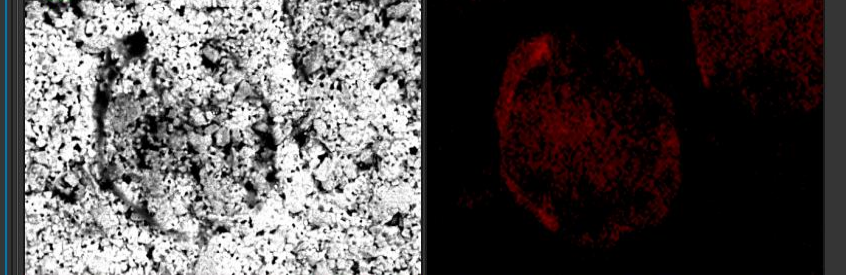
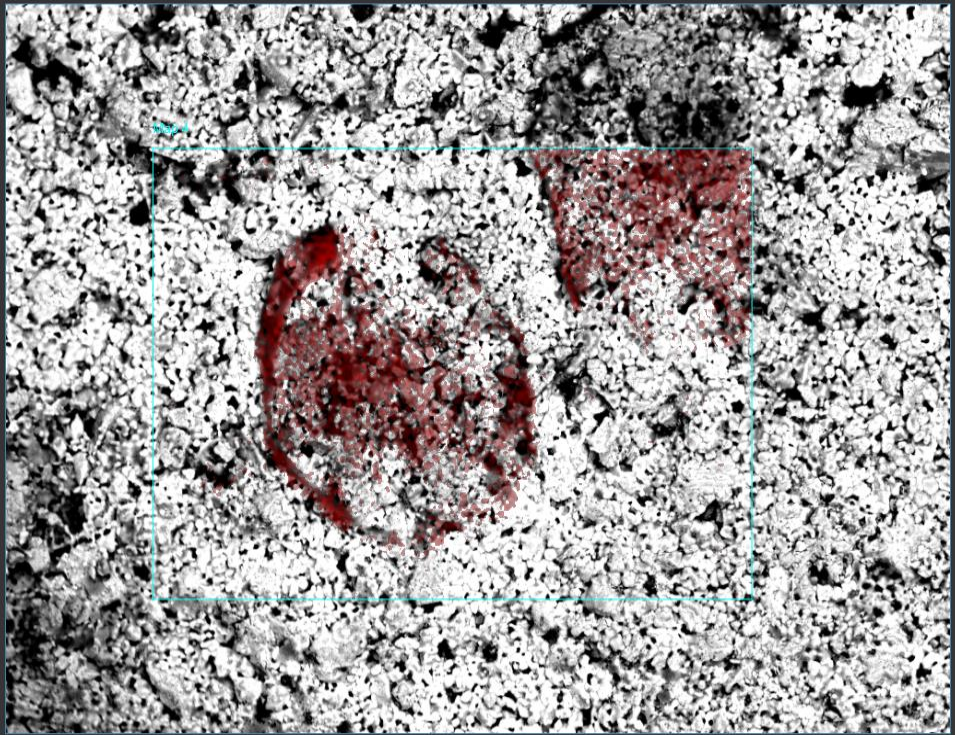
Imaged at 15 keV with SE(left, middle) and BSE (right) detector

SingleVac mode 4Q BSE Color



SingleVac mode
*„single click to charge
free imaging”*

Ceramic foam
Imaged at 20 keV



Carbon	K	65 % w
Zirconium	L	23 % w
Oxygen	K	11 % w
Magnesium	K	1 % w

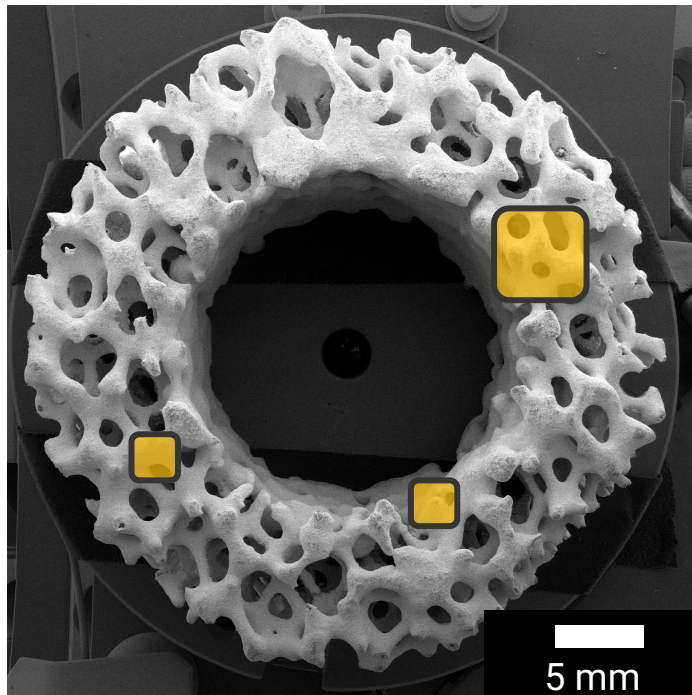


Essence EDS™

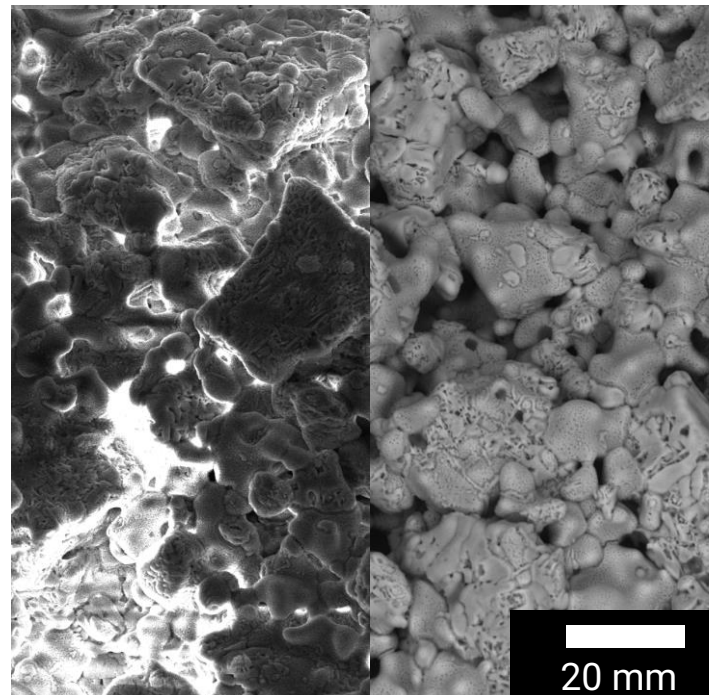
“Elemental results instantly available”

Market leading ease of use got even better

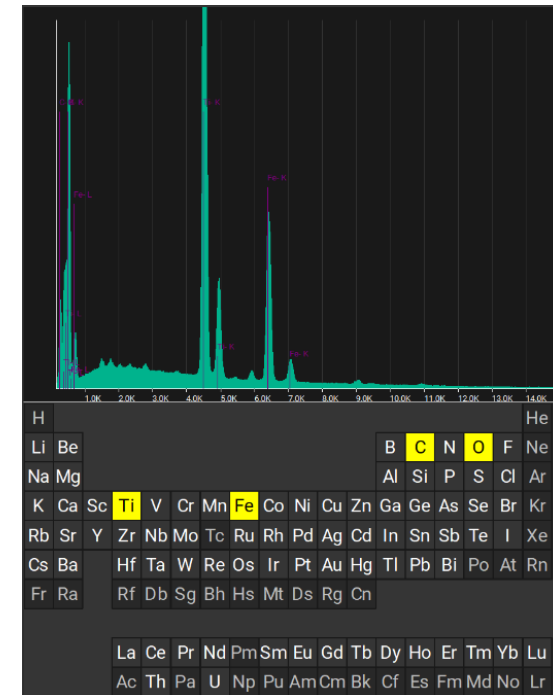
Wide Field Mode
„single click to locate
right features of interest”



SingleVac
„single click to
charge free imaging”



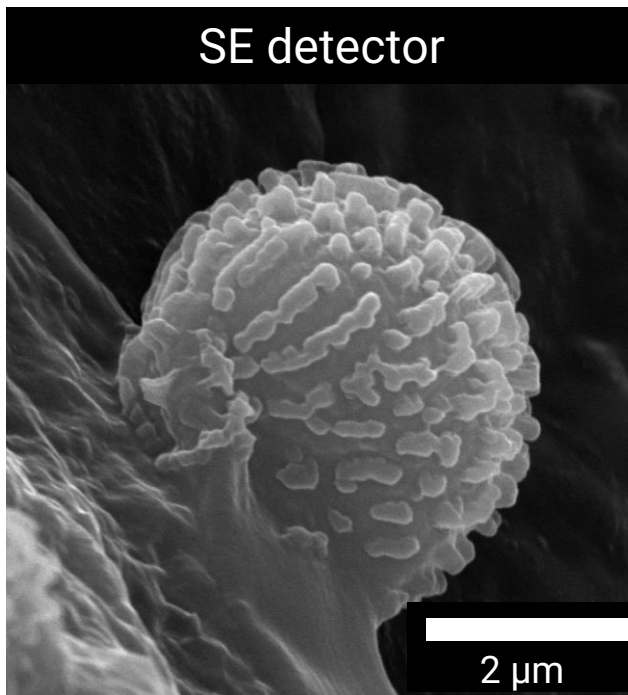
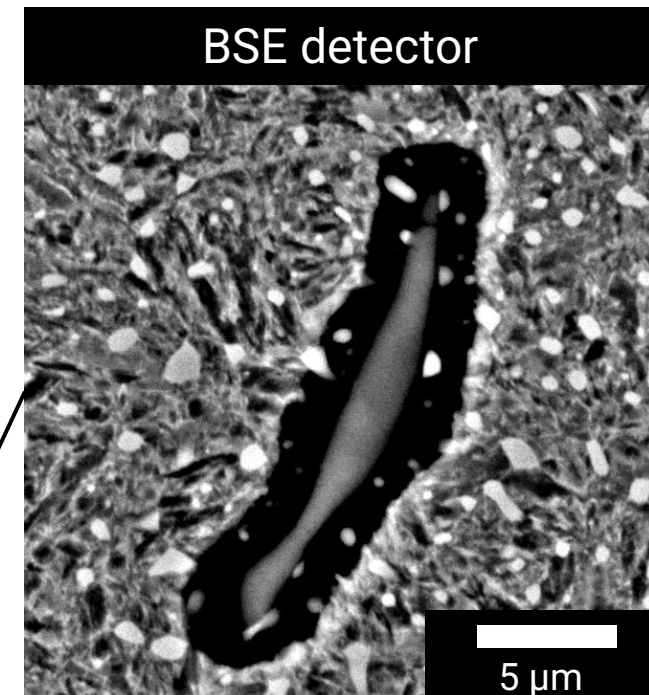
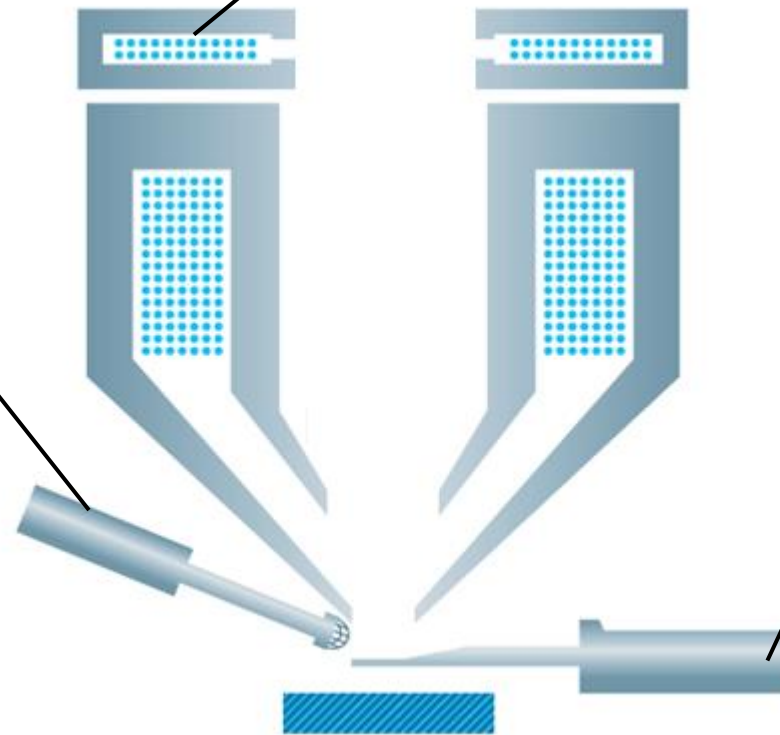
Essence™ EDS
„single click to
elemental results”



VEGA**Intermediate Lens™**

Provide access to the unique observation modes (WIDE FIELD, DEPTH and FIELD)

Used for fast setup of the beam - „Magnetic aperture “

**Topographical contrast****Material contrast**

Essence™ EDS

Essence™ EDS	
Acquisition modes:	Spectrum from region, point & ID, line scan and elemental mapping
EDS detector chip/window size	30 mm ²
Chip/window material	Si ₃ N ₄ window
Resolution	129 eV resolution @ Mn Ka
Number of puls processing settings	3
Maximum input count rate:	up to 1 000 000 CPS
Maximum output count rate:	up to 300 000 CPS
Quantification:	standardless, ZAF corrected
Report function	YES

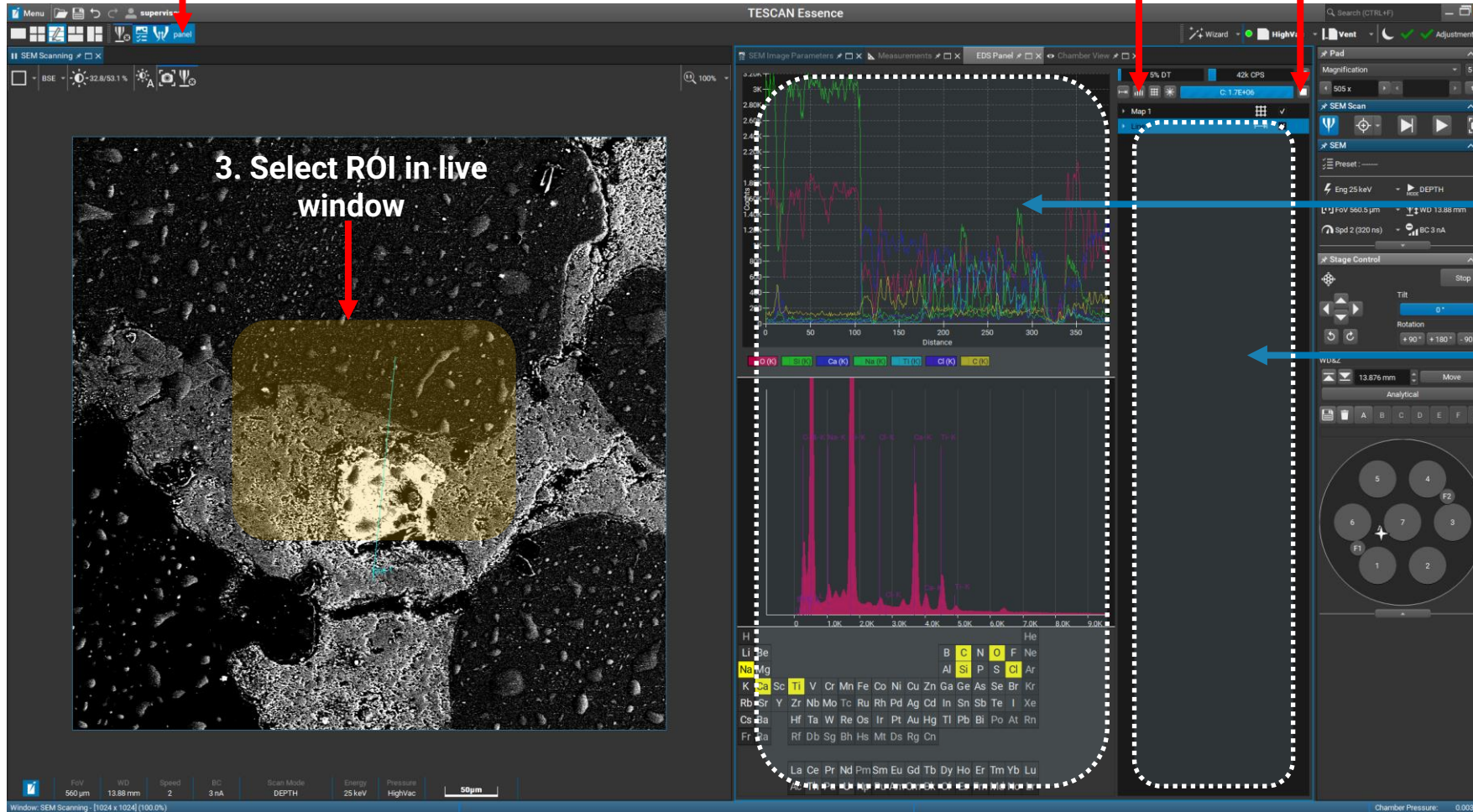
Essence™ EDS

1. Essence EDS button

2. Analysis type

4. start/stop

3. Select ROI in live window



Data visualization

Data storage in data tree
All data can be reported or batch exported in *.PNG and *.CSV formate